

High precision positioning platform

Customized platform product catalog

Suitable for industries such as semiconductor/photovoltaic/lithium battery/precision machine tool/medical equipment, etc





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Single axis precision linear platform



PM se	ries
PM115LS	16
PM165LS	18
PM190LS	
PM225LS	20
PM280LS	21



Single axis precision screw platform



PS series			
PS115LS	22		
PS165LS	24		
PS190LS	25		
PS225LS	26		
PS280LS	27		



Planar XY Cross Roller Platform



PlaneD-XYseries	
PLM-PlaneD-XY-150×150 29	9
PLM-PlaneD-XY-200×200 30	0
PLM-PlaneD-XY-250×250 30	0
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Flat track XY platform



	Plane-XY se	ries
6	PLM-Plane-XY-150	
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Plane Z-axis lifting platform



PlaneZ series
PLM-PlaneZ-10 37



Self balancing Z-direction motion table



ART-Z ser	ies	
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Large load Z-axis lifting platform



ZMS series PLM-ZMS-23 40





ZTT flat fine-tuning platform



ΖΤΤ	seri	es





Air floating turntable



QFML225 series PLM-QFML225-R 45

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Air floating single axis platform

	PLAM215 series
	PLAM215-100
	PLAM215-200
	PLAM215-300
	PLAM215-400
	PLAM215-500



Air floating single axis platform



PLAM385 series
PLAM385-100
PLAM385-200
PLAM385-300
PLAM385-400
PLAM385-500



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PLAM-XY series

PLAM-XY-300-300



Fixed beam gantry platform



DLXY series	
PDM-DLXY-400-400-100	
PDM-DLXY-600-600-100	
PDM-DLXY-800-800-100	







PlaneH series

PLM-PlaneH-XY-400



PDM-2K600-Z10-X160-Y1350-LDI







COMPANY PROFILE



TOKK Robot (Suzhou) Co., Ltd. is headquartered in Xiangcheng District, Suzhou City. Currently, it has three major research and development centers in Kunshan, Suzhou, and Shenzhen, with manufacturing bases in both Suzhou and Kunshan. The production area is over 30000 square meters, and there are dozens of R&D personnel with more than ten years of R&D experience.

At the same time, it integrates Lingchen Technology's years of motion control experience. The company focuses on the research and development, production, and sales of linear motors, precision platforms, transmission modules, electric cylinders, KK modules, servo presses, and other products. Targeting the high-end equipment manufacturing industry as the market, we have experts in mechanical, electronic automation, computer, industrial automation and other research fields, as well as young and promising scientific and technological personnel; Equipped with CNC machining centers, CNC milling machines, grinders, wire cutting machines, grinding machines and other equipment; Can meet the requirements of standardized mass production.

TOKK Robotics (Suzhou) Co., Ltd.'s products mainly serve major industries such as 3C, lithium batteries, photovoltaics, panels, and semiconductors. They are widely used in dispensing, handling, scanning, and moving, and can meet various customer needs and application scenarios.

The company will adhere to the principles of "customer achievement, win-win cooperation, craftsmanship spirit, reliability and altruism", with the mission of "becoming the preferred brand for global automation components", constantly exploring and innovating, striving to create a well-known brand with international competitiveness, and providing customers with high-quality services and support!



Corporate Vision

Committed to becoming the first/preferred supplier of components in the global automation field

corporate values

We provide customers with diversified, customized, and high-quality services!

service tenet

The second line serves the first line, and everyone serves the customers.

Single-axis air-bearing stage

Model Naming Rules



Application scenarios

Large optical lens inspection, wafer defect detection in the semiconductor field, precision manufacturing and packaging, etc

Product Introduction



 Can be used as a single axis or combined with other axes to form a multi axis system

Very suitable for applications with heavy loads

 Ottilizing air elastic potential energy as a supporting guide rail to achieve zero friction between the slide rail and the sliding table
Excellent dynamic performance and positioning accuracy
Positive and negative pressure design of air flotation platform
Large volume loads with uneven distribution of gravity on air
floating guide rails
Application can better ensure the normal air gap of the air guide rail

istomizatic

Larger itinerary can be customized

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Air floating single axis platform PLAM215 series

Parameter Table

Platform model	PLAM215-100	PLAM215-200	PLAM215-300	PLAM215-400	PLAM215-500	
Effective stroke	100mm	200mm	300mm	400mm	500mm	
positioning accuracy	±0.2 μm	±0.3 μm	±0.3 μm	±0.4 μm	±0.5 μm	
Bi directional repetitive positioning	^{accuracy} ±0.1 μm	±0.1 μm	±0.2 μm	±0.25µm	±0.3 μm	
pitch	±1.5 arc sec	±2.5 arc sec	±3 arc sec	±4 arc sec	±5 arc sec	
yaw	±1.5 arc sec	±2.5 arc sec	±3 arc sec	±4 arc sec	±5 arc sec	
roll	±1.5 arc sec	±2.5 arc sec	±3 arc sec	±4 arc sec	±5 arc sec	
Straightness	±0.5 μm	±0.6 μm	±0.75 μm	±1.5 μm	±2 μm	
Flatness	±0.5 μm	±0.6 μm	±0.75 μm	±1.5 μm	±2 μm	
resolution			1nm			
Maximum acceleration			2 g			
maximum speed			1000 mm/s			
Maximum horizontal load			35 kg			
Maximum radial load			20 kg			
Continuous thrust			78 N			
Peak thrust			432 N			
on-bottom stability			±10 nm			
Working pressure		5.5 bar (recommended dry air, filter water and oil, filter dust to below 0.5 μ m)				
Platform quality	19.1kg	21.3kg	23.5kg	25.7kg	27.9kg	
Platform material			Aluminium			
mean time between failures	ean time between failures 25000Hours					









Single-axis air-bearing stage

Model Naming Rules



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Large volume loads with uneven distribution of gravity on air
floating guide rails
Application can better ensure the normal air gap of the air guide rail

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Air floating single axis platform

PLAM385 series

Parameter Table

Platform model	PLAM385-100	PLAM385-200	PLAM385-300	PLAM385-400	PLAM385-500
Effective stroke	100mm	200mm	300mm	400mm	500mm
positioning accuracy	±0.2 μm	±0.3 μm	±0.3 μm	±0.4 μm	±0.5 μm
Bi directional repetitive positioning	accuracy $\pm 0.1\mu m$	±0.1 μm	±0.2 μm	±0.25μm	±0.3 μm
pitch	\pm 1.5 arc sec	\pm 2.5 arc sec	±3 arc sec	±4 arc sec	±5 arc sec
yaw	\pm 1.5 arc sec	\pm 2.5 arc sec	±3 arc sec	±4 arc sec	±5 arc sec
roll	\pm 1.5 arc sec	\pm 2.5 arc sec	±3 arc sec	±4 arc sec	±5 arc sec
Straightness	±0.5 μm	±0.6 μm	±0.75 μm	±1.5 μm	±2μm
Flatness	±0.5 μm	±0.6 μm	±0.75 μm	±1.5 μm	±2μm
resolution			1nm		
Maximum acceleration			2 g		
maximum speed			1000 mm/s		
Maximum horizontal load			60 kg		
Maximum radial load			30 kg		
Continuous thrust			156 N		
Peak thrust			864 N		
on-bottom stability			±10 nm		
Working pressure	5.5 bar(Recommended dry air, filter water and oil, filter dust to below 0.5 μ m)				
Platform quality	40.9kg	46.2kg	51.5kg	56.8kg	62.1kg
Platform material			Aluminium		
mean time between failures			25000Hours		

External dimensions







Superimposed air-bearing stage

Model Naming Rules



Application scenarios

Large optical lens inspection, wafer defect detection in the semiconductor field, precision manufacturing and packaging, etc

Product Introduction



Can be used as a single axis or combined with other axes to form multi axis system

Very suitable for applications with heavy loads

 Ottilizing air elastic potential energy as a supporting guide rail to achieve zero friction between the slide rail and the sliding table
Excellent dynamic performance and positioning accuracy
Positive and negative pressure design of air flotation platform
Large volume loads with uneven distribution of gravity on air
floating guide rails
Application can better ensure the normal air gap of the air guide rail

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Overlay air flotation platform

PLAM-XY series



Parameter Table

Platform model		PLAM-XY-300-300				
Effective stroke		300mm*300mm				
positioning accuracy		±0.3 µm				
Bi directional repetitive positioning a	ccuracy	±0.2 µm				
pitch		±3 arc sec				
yaw		±3 arc sec				
roll		±3 arc sec				
Straightness		±1 µm				
Flatness		±1 µm				
resolution		1nm				
Maximum acceleration		2 g				
maximum speed		1000 mm/s				
Maximum horizontal load		60 kg				
Maximum radial load		30 kg				
Continuous thrust	Upper shaft	78 N				
Continuous trifust	lower shaft	156 N				
Deals the set	Upper shaft	432 N				
Peak Infusi	lower shaft	864 N				
on-bottom stability		±10 nm				
Working pressure		5.5 bar (recommended dry air, filter water and oil, filter dust to below 0.5 μ m)				
Platform quality		75kg				
Platform material		Aluminium				
mean time between failures		25000Hours				









Single-axis precision linear stage

Parameter Table



Application scenarios

OLED cutting/PCB drilling/CNC machining/biotechnology/IC packaging/wafer inspection

Product Introduction



- High performance and low-cost solution
- High rigidity mechanical structure
- Flexible configuration options (with different travel and width options)
 - The maximum travel distance can reach 1000mm
 - Excellent cable management

Structural characteristics

- · Driven by a linear motor
- · Fast speed
- · Good dynamic performance
- · Low friction force
- · Easy to achieve precise position control
- · Very suitable for applications with large travel, high precision, and high speed

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Single axis precision linear platform PM115LS specification

Parameter Table

Platform model	PM115LS-50	PM115LS-100	PM115LS-150	PM115LS200	PM115LS-250	PM115LS-300	
Effective stroke	50 mm	100 mm	150 mm	200 mm	250 mm	300 mm	
positioning accuracy	±0.75 μm	±1 μm	±1µm	±1.5 µm	±1.5 μm	±1.5 μm	
Bi directional repetitive positioning accuracy	±0.4 μm	±0.4 μm	±0.4 μm	±0.5 μm	±0.5 μm	±0.5 μm	
pitch	4 arc sec	6 arc sec	8 arc sec	10 arc sec	11 arc sec	12 arc sec	
yaw	4 arc sec	6 arc sec	8 arc sec	10 arc sec	11 arc sec	12 arc sec	
roll	4 arc sec	6 arc sec	8 arc sec	10 arc sec	11 arc sec	12 arc sec	
Straightness	±1.5 μm	±2.5 μm	±3 μm	±4 μm	±5 μm	±6 μm	
resolution			100 nm				
Maximum acceleration			2 m/s				
maximum speed			3 g				
Maximum horizontal load			40 KG				
Maximum radial load			40 KG				
Continuous thrust			26 N				
Peak thrust			144 N				
Minimum step quantity			75 nm				
Platform quality 5.1 kg	5.7 kg	6.2 4	kg 6	.8 kg	7.4 kg	8.1 kg	
Platform material	Aluminium						
mean time between failures			20000 Hours				

Note: The above test data was obtained from a linear amplifier in a laboratory environment, with the test point located 25mm above the center point











Single axis precision linear platform PM165LS specification



pitch

yaw

roll



Note: The above test data was obtained from a linear amplifier in a laboratory environment, with the test point located 25mm above the center point











Single axis precision linear platform

PM190LS specification



Parameter Table

Platform model	PM190LS -100	PM190LS -200	PM190LS -300	PM190LS -400	5 PM190LS -500	PM190LS -600	PM190LS -800	PM190LS -1000
Effective stroke	100	200	300	400	500	600	700	800
positioning accuracy	±1µm	±1 µm	±1 μm	±1 μm	±1 μm	±1 μm	±1.5 μm	±1.5 μm
Bi directional repetitive positioning accuracy	±0.3µm	±0.4 μm	±0.4 μm	±0.4 μm	±0.4 μm	±0.4 μm	±0.5 μm	±0.5 μm
pitch	6 arc sec	8 arc sec	10.5 arc sec	12 arc sec	14 arc sec	16 arc sec	20 arc sec	24 arc sec
yaw	6 arc sec	8 arc sec	10.5 arc sec	12 arc sec	14 arc sec	16 arc sec	20 arc sec	24 arc sec
roll	6 arc sec	8 arc sec	10.5 arc sec	12 arc sec	14 arc sec	16 arc sec	20 arc sec	24 arc sec
Straightness	±1.5µm	±2.5 μm	±3.5 μm	±4.5 μm	±5.5 μm	±6.5 µm	±8 μm	±10 µm
resolution				100 nm				
Maximum acceleration				3 g				
maximum speed				2 m/s				
Maximum horizontal load				45 kg				
Maximum radial load				45 kg				
Continuous thrust				130 N				
Peak thrust				720 N				
Minimum step quantity				75 nm				
Platform quality 14.5	5 kg 16.8	kg 1	9.4 kg 2	1.8 kg	24.2 kg	26.6 kg	29.4 kg	32 kg
Platform material				Aluminium				
mean time between failures				27000 Hours				

Note: The above test data was obtained from a linear amplifier in a laboratory environment, with the test point located 25mm above the center point











Single axis precision linear platform

PM225LS specification

Parameter Table



Platform model	PM225LS -100	PM225LS -200	PM225LS -300	PM225LS -400	PM225LS -500	PM225LS -600	PM225LS -800	PM225LS -1000
Effective stroke	100	200	300	400	500	600	700	800
positioning accuracy	±1 μm	±1 μm	±1 μm	±1 μm	±1 μm	±1 μm	±1.5 μm	±1.5 μm
Bi directional repetitive positioning accuracy	^l ±0.3 μm	±0.4 μm	±0.4 μm	±0.4 μm	±0.4 μm	±0.4 μm	±0.5 μm	±0.5 μm
pitch	6 arc sec	8 arc sec	10.5 arc sec	14 arc sec	15 arc sec	18 arc sec	20 arc sec	24 arc sec
yaw	6 arc sec	8 arc sec	10.5 arc sec	14 arc sec	15 arc sec	18 arc sec	20 arc sec	24 arc sec
roll	6 arc sec	8 arc sec	10.5 arc sec	14 arc sec	15 arc sec	18 arc sec	20 arc sec	24 arc sec
Straightness	±2.5 µm	±4 μm	±4.5 μm	±7.5 μm	±8 μm	±9 μm	±10 μm	±12 µm
resolution	100 nm							
Maximum acceleration				3 g				
maximum speed				2 m/s				
Maximum horizontal load				45 kg				
Maximum radial load				45 kg				
Continuous thrust				204 N				
Peak thrust				1152 N				
Minimum step quantity				100 nm				
Platform quality	14.5 kg	16.8 kg	19.4 kg	21.8 kg	24.2 kg	26.6 kg	29.4 kg	32 kg
Platform material				Aluminiu	m			
mean time between failures	27000 Hours							

Note: The above test data was obtained from a linear amplifier in a laboratory environment, with the test point located 25mm above the center point











Single axis precision linear platform

PM280LS specification

Parameter Table



Platform model	PM280LS-300	PM280LS-400	PM280LS-500	PM280LS-600	PM280LS-700	PM280LS-800			
Effective stroke	300 mm	400 mm	500 mm	600 mm	700 mm	800 mm			
positioning accuracy	±1 µm	±1 μm	±2 μm	±2 μm	±2 μm	±2 μm			
Bi directional repetitive positionin accuracy	^{ig} ±0.5 μm	±0.5 μm	±0.6 µm	±0.6 µm	±0.6 μm	±0.8 μm			
pitch	12 arc sec	16 arc sec	18 arc sec	20 arc sec	22 arc sec	25 arc sec			
yaw	12 arc sec	16 arc sec	18 arc sec	20 arc sec	22 arc sec	25 arc sec			
roll	12 arc sec	16 arc sec	18 arc sec	20 arc sec	22 arc sec	25 arc sec			
Straightness	±4 μm	±4 μm	±6 μm	±6.5 μm	±7 μm	±8 μm			
resolution	100 nm								
Maximum acceleration	3 g								
maximum speed			2 m/	s					
Maximum horizontal load			150 k	g					
Maximum radial load			150 k	g					
Continuous thrust			255 I	N					
Peak thrust			1440	N					
Minimum step quantity			200 n	m					
Platform quality	55 kg	60 kg	65 kg	71 kg	76 kg	81 kg			
Platform material	Aluminium								
mean time between failures	27000 Hours								

Note: The above test data was obtained from a linear amplifier in a laboratory environment, with the test point located 25mm above the center point









Single-axis precision linear stage

Parameter Table



Application scenarios

OLED cutting/PCB drilling/CNC machining/biotechnology/IC packaging/wafer inspection

Product Introduction



		L
Stri i	·Adopting AC brushless servo motor and screw drive	
tural	·The maximum speed can reach 300mm/s	
char	\cdot The PS series can meet the horizontal placement of linear axes for us	e
otac	·After selecting the power-off self-locking brake configuration	
rictic	·The PS series can be used as a Z-axis platform	
0	·Can be used in conjunction with the PM series	

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PS115LS series specifications



Parameter Table

Platform	n model	PS115LS-50	PS115LS-100	PS115LS-150	PS115LS200	PS115LS-250	PS115LS-300		
Effectiv	e stroke	50mm	100mm	150mm	200mm	250mm	300mm		
positioning	Grating ruler	±0.8µm	±1µm	±1µm	±1.5µm	±1.5µm	±1.5µm		
accuracy	Rotary encode	΄ ±1μm	±1µm	±1µm	±1.5µm	±1.5µm	±1.5µm		
Bi directional	Grating ruler	±0.3µm	±0.3µm	±0.35µm	±0.4µm	±0.45µm	±0.5µm		
positioning accuracy	, Rotary encode	±0.6µm	±0.8µm	±0.8µm	±1µm	±1µm	±1µm		
pitch	pitch		6arc sec	7arc sec	8arc sec	9arc sec	10arc sec		
yaw		4arc sec	6arc sec	7arc sec	8arc sec	9arc sec	10arc sec		
roll	roll		6arc	7arc sec	8arc sec	9arc sec	10arc sec		
Stra	ightness	±2µm	±2.5µm	±3µm	±3.5µm	±4µm	±4.5µm		
	Grating ruler	1nm, 100nm, 0.1µm							
resolution	Rotary encode	·		23	3bit				
M	Horizontal plac	ement		4	Okg				
Maximum Load	Vertical placem	ient		2	Okg				
Minimu	ım step quantity			100nm,	0.1µm				
Platfor	Platform quality		5.7kg	6.2kg	6.8kg	7.4kg	8.1kg		
Platfor	Platform material			Aluminium					
mean t	mean time between failures			27000 Hours					

Note: The above test data was obtained from a linear amplifier in a laboratory environment, with the test point located 25mm above the center point











PS165LS series specifications



Parameter Table

PI	atform model	PS165LS50	PS165LS100	PS165LS150	PS165LS200	PS165LS300	PS165LS400		
Ef	fective stroke	100 mm	200 mm	300 mm	400 mm	500 mm	600 mm		
positionina	Grating rul	er ±1 µm	±1 μm	±1.5 μm	±2 μm	±2 μm	±2 μm		
accuracy	Rotary end	oder ±1.5 µm	±1.5 μm	±1.5 μm	±2 μm	±2 μm	±2 μm		
Bi directional	Grating rul	er ±0.3 μm	±0.35 μm	±0.4 μm	±0.45 μm	±0.5 μm	±0.6 μm		
repetitive positioning acc	uracy Rotary end	oder ±1 µm	±1 μm	±1 μm	±1.5 μm	±1.75 μm	±2 μm		
	pitch	6 arc sec	7 arc sec	8 arc sec 8 arc sec 8 arc sec	9 arc sec 9 arc sec 9 arc sec	10 arc sec	11 arc sec		
	yaw	6 arc sec	7 arc sec			10 arc sec	11 arc sec 11 arc sec		
	roll	6 arc sec	7 arc sec			10 arc sec			
	Straightness	± 2µm	±2.5 μm	±3 μm	±3.5 μm	±4 μm	±5 μm		
	Grating rul	er		1 nm,100 nm,0.1 μm					
resolution	Rotary end	oder		23	bit				
	maximum s	peed		300	m/s				
	Horizontal pla	acement		45	5 kg				
Maximum Loa	d Vertical place	ment		25	5 kg				
Mir	nimum step quanti	ty		100 nm,	1 µm				
Pla	tform quality	7 kg	7.5 kg	8 kg	9 kg	10 kg	11 kg		
Pla	tform material		Aluminium						
me	an time between f	failures							

Note: The above test data was obtained from a linear amplifier in a laboratory environment, with the test point located 25mm above the center point











PS190LS series specifications



Parameter Table

Platfo	rm model	PS190LS -100	PS190LS -150	PS190LS -200	PS190LS -250	PS190LS -300	PS190LS -400	PS190LS -500	PS190LS -600
Effecti	ve stroke	100	200	300	400	500	600	700	800
positioning	Grating ruler	±1 µm	±1.2 μm	±1.2 μm	±1.5 μm	±1.5 μm	±1.75 μm	±1.75 μm	±2 μm
accuracy	Rotary enco	^{der} ±1.2 µm	±1.2 μm	±1.75 μm	±1.75 μm	±1.75 μm	±2 μm	±2 μm	±2.5 μm
Bi directional repetitive	Grating ruler	±0.3 µm	±0.5 μm	±0.5 μm	±0.5 μm	±0.6 μm	±0.6 µm	±0.7 μm	±0.7 μm
positioning accuracy	/ Rotary enco	der ±1 µm	±1 μm	±1 μm	±1.5 μm	±1.5 μm	±1.5 μm	±1.5 μm	±1.5 μm
pitch		8 arc sec	9 arc sec	10 arc sec	11 arc sec	12 arc sec	13 arc sec	14 arc sec	15 arc sec
yav	N	8 arc sec	9 arc sec	10 arc sec	11 arc sec	12 arc sec	13 arc sec	14 arc sec	15 arc sec
roll	roll		9 arc sec	10 arc sec	11 arc sec	12 arc sec	13 arc sec	14 arc sec	15 arc sec
Str	aightness	±2.5 μm	±3 μm	±3.5 μm	±4 μm	±4.5 μm	±5 μm	±5.5 μm	±6.5 μm
	Grating ruler			1 nm,100 nm,0.1 um					
resolution	Rotary enco	der		23 bit					
	maximum sp	eed		300 mm/s					
	Horizontal plac	ement			60	kg			
Maximum Load	Vertical placem	ient			40	kg			
Minimu	m step quantity				100 nm,	1 um			
Platforn	n quality	12 kg	12.5 kg	13 kg	14 kg	15 kg	16 kg	17 kg	18 kg
Platforn	Platform material			Aluminium					
mean ti	mean time between failures				27000 Hours				

Note: The above test data was obtained from a linear amplifier in a laboratory environment, with the test point located 25mm above the center point











PS225LS series specifications



Parameter Table

Pla	atform model	PS225LS -100	PS225LS -150	PS225LS -200	PS225LS -300	PS225LS -400	PS225LS -500	PS225LS -600	PS225LS -800
Eff	fective stroke	100	200	300	400	500	600	700	800
positioning	Grating	uler ±1µm	±1.2µm	±1.5µm	±1.5µm	±1.75µm	±2µm	±2.5µm	±2.5µm
accuracy	Rotary e	ncoder ±1µm	±1µm	±1.5µm	±1.5µm	±1.75µm	±2µm	±2.5µm	±2.5µm
Bi directional repetitive	Grating	uler ±0.35µm	±0.4µm	±0.5µm	±0.5µm	±0.6µm	±0.6µm	±0.75µm	±0.75µm
positioning accu	racy Rotary e	ncoder ±1µm	±1µm	±1µm	±1.5µm	±1.5µm	±1.5µm	±1.5µm	±1.5µm
	pitch		8 arc sec	9 arc sec	10 arc sec	11 arc sec	12 arc sec	15 arc sec	18 arc sec
	yaw		8 arc sec	9 arc sec	10 arc sec	11 arc sec	12 arc sec	15 arc sec	18 arc sec
	roll		8 arc sec	9 arc sec	10 arc sec	11 arc sec	12 arc sec	15 arc sec	18 arc sec
	Straightness		±3µm	±3.5µm	±4µm	±5µm	±6µm	±8µm	±9µm
	Grating	uler		1nm, 10nm, 0.1µm					
resolution	Rotary e	ncoder		2	23bit				
	maximur	n speed		300	mm/s				
	Horizontal	placement		1	00KG				
Maximum Load	d Vertical pla	cement		6	60KG				
Mini	mum step quar	ntity		100n	m,1µm				
Plat	form quality	20kg	22kg	24kg	25kg	26.5kg	29kg	32kg	35kg
Plat	form material			Aluminium					
mea	mean time between failures			27000) Hours				

Note: The above test data was obtained from a linear amplifier in a laboratory environment, with the test point located 25mm above the center point











Single axis precision screw platform

PS280LS series specifications

Parameter Table

Pl	atform model	PS280LS-300	PS280LS-400	PS280LS-500	PS280LS-600	PS280LS-700	PS280LS-800			
Ef	fective stroke	300 mm	400 mm	500 mm	600 mm	700 mm	800 mm			
positioning	Grating ruler	±2.5 μm	±2.5 μm	±2.5 μm	±2.75 μm	±2.75 μm	±3 μm			
accuracy	Rotary encod	^{er} ±2.5 μm	±3 μm	±3 μm	±3 μm	±3.5 μm	±3.5 μm			
Bi directional	Grating ruler	±0.6 μm	±0.65 μm	±0.65 μm	±0.7 μm	±0.75 μm	±0.8 μm			
positioning accu	racy Rotary encod	^{er} ±1.5 µm	±1.5 μm	±1.5 μm	±1.5 μm	±1.5 µm	±1.5 μm			
	pitch	12 arc sec	16 arc sec	18 arc sec	20 arc sec	22 arc sec	25 arc sec			
	yaw	12 arc sec	16 arc sec 16 arc sec	18 arc sec 18 arc sec	20 arc sec 20 arc sec	22 arc sec 22 arc sec	25 arc sec 25 arc sec			
	roll	12 arc sec								
	Straightness ±4 µm		±5 μm	±6 μm	±7 μm	±8 μm	±10 μm			
recolution	Grating ruler									
resolution	Rotary encod	er	23 bit							
	maximum spe	ed		300	mm/s					
	Horizontal place	ment		1	20 kg					
Maximum Load	d Vertical placeme	ent		-	70 kg					
Min	imum step quantity			100 nn	n, 1µm					
Plat	Platform quality		60 kg	65 kg	71 kg	76 kg	81 kg			
Plat	form material									
mea	an time between failu	res		27000 Hours						

Note: The above test data was obtained from a linear amplifier in a laboratory environment, with the test point located 25mm above the center point











Plane XY cross roller stage

Parameter Table



Application scenarios

Industrial and scientific research projects that require nanometer level positioning accuracy, such as laser processing/flying shot scanning detection/measurement detection/surface roughness detection/laser cutting, etc

Product Introduction



ustomizat



Planar XY Cross Roller Platform

PlaneD-XY series specifications

Parameter Table

Platform model	PLM-PlaneD-XY150×150	PLM-PlaneD-XY200×200	PLM-PlaneD-XY250×250	PLM-PlaneD-XY300×300					
Effective stroke	100 mm×100 mm	150 mm×150 mm	200 mm×200 mm	250 mm×250 mm					
positioning accuracy	±0.3 µm	±0.4 µm	±0.5 μm	±0.6 µm					
Bi directional repetitive positioning accuracy	±0.1 µm	±0.15 μm	±0.2 μm	±0.25 μm					
pitch	15 arc sec	16 are sec	18 are sec	20 are sec					
yaw	15 arc sec	16 are sec	18 are sec	20 are sec					
Straightness	±1.5 μm	±2 μm	±2.5 μm	±3 μm					
resolution		1 nm							
Maximum acceleration		1.	5 g						
maximum speed		800 m	m/s						
Maximum horizontal loa	d 20 KG	20 KG	25 KG	30 KG					
Continuous thrust		73 N		292 N					
Peak thrust		250 N		1000 N					
Minimum step quantity		5 r	m						
Platform quality	26 KG	29 KG	35 KG	50 KG					
Platform material		Alum	inium						
mean time between failu	ires	27000	Hours						

Note: The above test data was obtained from a linear amplifier in a laboratory environment, with the test point located 25mm above the center point









PLM-PlaneD-XY200×200 External dimensions



PLM-PlaneD-XY250×250 External dimensions

















Plane linear rail XY stage

Parameter Table



Application scenarios

Industrial fields and scientific research projects that require nanometer level positioning accuracy, such as measurement, wafer inspection, surface roughness detection, laser cutting, etc

Product Introduction



Customizatio



Flat track XY platform

Plane-XY series specifications

Parameter Table

Platform model	PLM-Plane-XY-150	PLM-Plane-XY-250	PLM-Plane-XY-350		
Effective stroke	150 mm×150 mm	250 mm×250 mm	350 mm×350 mm		
positioning accuracy	±0.3 µm	±0.3 μm	±0.3 μm		
Bi directional repetitive positioning accuracy	±0.15 μm	±0.15 µm	±0.15 μm		
pitch	7 arc sec	9 are sec	11 are sec		
yaw	7 arc sec	9 are sec	11 are sec		
Straightness	±1.5 μm	±2 μm	±2.5 μm		
resolution		1 nm			
Maximum acceleration		2 g			
maximum speed		2000 mm/s			
Maximum horizontal load	45 KG	45 KG	45 KG		
Continuous thrust	Upper axis: 153 N Lower axis: 306 N				
Peak thrust	Upper axis: 864 N Lower axis: 1728 N				
Minimum step quantity		20 nm			
Platform quality	30 KG	40 KG	50 KG		
Platform material		Aluminium			
mean time between failures		27000 Hours			

Note: The above test data was obtained from a linear amplifier in a laboratory environment, with the test point located 25mm above the center point

PLM-Plane-XY150×150 External dimensions











PLM-Plane-XY250×250 External dimensions







125

NORMAL TRAVEL

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PLM-Plane-XY350×350 External dimensions













Plane Z axis lifting stage

Parameter Table



Application scenarios

Photolithography, detection and packaging, contour measurement in the semiconductor field, gene sequencing in the biomedical field, etc

Product Introduction

	·Vertical motion Z-axis platform with nanometer level positioning accuracy		·High precision direct drive lifting platform
Pr	·Linear motor drive	Stru	High dynamic performance (no-load cut-off frequency greater than 120Hz)
Adopting cross roller guide rail		ictura	·Low lateral height, suitable for compact space applications
t Fea	·Has excellent dynamic performance and positioning accuracy	al cha	Built in pneumatic balance, maximum load 15kg
ature	·Resolution of 1nm	aracte	·Can form a multi axis system with Surface Meta or linear axis
·Repe	·Repetitive positioning accuracy ± 100nm	eristio	In situ stability of 5nm (equipped with linear driver and isolated laboratory environment)
	·Positioning accuracy ± 200nm	ы	

L L Lustomizati


Plane Z-axis lifting platform PlaneZ series specifications



Parameter Table

Platform model	PLM-PlaneZ-10	
Effective stroke	10 mm	
Absolute positioning accuracy	±300 nm	
Bi directional repetitive positioning accuracy	±150 nm	
pitch	20 arc sec	
yaw	20 arc sec	
Straightness	±2 μm	
Maximum Load	8 kg	
resolution	1 nm	
Minimum step quantity	5 nm	
on-bottom stability	5 nm	
maximum speed	5 mm/s	
Maximum acceleration	0.7 g	
Continuous thrust	20 N	
Peak thrust	45 N	
Platform quality	6.2 kg	
Gas supply requirements	80psi \pm 5psi, with an air filter less than 0.25 μ m	
Platform material	Aluminium	
mean time between failures	20000 Hours	

Remarks:

Measure parallel or perpendicular to the direction of the wedge block;
 No load test;

(2) Adaptation - AS feedback, configure linear amplifier;(4) Other itineraries can be customized.

(5) The default test point position is 25 mm above the tabletop, and the performance indicators of single axis and multi axis systems are related to the actual load and working point position;

Overall dimension









Self-balancing Z direction motion stage

Parameter Table



Application scenarios

Fiber optic coupling in the communication field, circular crystal defect detection in the semiconductor field, gene sequencing in the biomedical field, and laser micro nano processing, etc

Product Introduction







Self balancing Z-direction motion table ART-Z series specifications

Parameter Table

Platform model	PLM-ART-Z-040	PLM-ART-Z-100	PLM-ART-Z-160
Effective stroke	40 mm	100 mm	160 mm
positioning accuracy	±0.3 µm	±0.4 µm	±0.5 µm
Bi directional repetitive positioning accuracy	±0.1 μm	±0.2 µm	±0.25 μm
pitch	10 arc sec	12 arc sec	12 arc sec
yaw	10 arc sec	10 arc sec	10 arc sec
roll	10 arc sec	10 arc sec	10 arc sec
Straightness	±2 μm	±2 μm	±2.5 μm
Flatness	±2 μm	±2 μm	±2.5 μm
resolution		1 nm	
Minimum step quantity		5 nm	
on-bottom stability		3 nm	
Maximum acceleration		500 m/s	
maximum speed		1 g	
Maximum horizontal load		12 KG	
Continuous thrust		52 N	
Peak thrust		288 N	
Platform quality	2.7 kg	3.9 kg	5.2 kg
Platform material		Aluminium	
mean time between failures		20000 Hours	

REMARKS:

(1) Adaptation - ASH feedback, linear amplifier;

(2) No load, corresponding power amplifiers need to be configured;

(3) The default test point position is 25 mm above the tabletop, and the performance indicators of single axis and multi axis systems are related to the actual load and working point position;
(4) The cylinder gas supply needs to be equipped with a triple air filter, which must be clean, dry, and filtered to particles below 0.25um. It is recommended to use ammonia gas with a purity of 99.9%. The air pressure can be adjusted according to the actual load weight of the platform.

(5) Other itineraries can be customized.

PLM-ART-Z-160 External dimensions







Large load Z axis lifting stage

Parameter Table



Application scenarios

Defect detection, optical lens inspection, and precision machining in the semiconductor field provide Z-direction precision positioning for it

Product Introduction



Adopung a wedge-snaped litting mechanism
·Directly moving the load
·Within a long range of movement
·Maintain the shortest possible height
Optimized the impact of system errors
Helps improve overall accuracy performance

Customization	Larger itinerary can be customized	



Large load Z-axis lifting platform ZMS series specifications



Parameter Table

Platform model	PLM-ZMS-23	
Effective stroke	23mm	
positioning accuracy	±2µm	
Bi directional repetitive positioning accuracy	±1µm	
Straightness	±2µm	
resolution	0.1µm	
Maximum acceleration	2g	
maximum speed	30mm/s	
Maximum horizontal load	60KG	
Platform quality	50KG	
Platform material	Aluminium	
mean time between failures	27000 Hours	

Note: The above test data was obtained from a linear amplifier in a laboratory environment, with the test point located 25mm above the center point

External dimensions











ZTT plane fine adjustment stage

Model Naming Rules



Application scenarios

Light source alignment/wafer inspection and other fields

Product Introduction







ZTT flat fine-tuning platform

ZTT series specifications

arameter Table			
Platform model		PLM-ZTT-4	
axial	Z	θΧ	θΥ
Effective stroke	4	2°	2°
oositioning accuracy	±0.5 μm	-	-
epeatability	±0.25 μm	±1.5 arc sec	±1.5 arc sec
bitch	±10 arc sec	-	-
/aw	±10 arc sec	-	-
Straightness	±1.5 μm	-	-
latness	±1.5 μm	-	-
naximum speed	1 g	-	-
Maximum acceleration	200mm/s	-	-
/inimum step quantity	100nm	1arc sec	1 arc sec
Maximum Load		10Kg	
Platform quality		6.5Kg	
Platform material		Aluminium	
nean time between failures		27000 Hours	

Note: The above test data was obtained from a linear amplifier in a laboratory environment, with the test point located 25mm above the center point





Air floating motor

Application scenarios

Industrial fields and scientific research projects that require angular second level positioning accuracy, such as measurement and detection, biological sample processing and observation, synchronous acceleration research, precision manufacturing, optical alignment, and system calibration

Product Introduction



Customizat

Larger itinerary can be customized



Air floating direct drive rotating platform

PLM-QFML225-R specification



Parameter Table

Platform model	PLM-QFML225-R	
Turntable travel	360°	
Carrier diameter	210 mm	
height	70 mm	
Corner accuracy	±2 arc sec	
repeatability	±0.5 arc sec	
Axis jump	250 nm	
End jump	300 nm	
Minimum step quantity	0.5 arc sec	
on-bottom stability	0.5 arc sec	
Continuous torque	20 N.M	
Peak torque	40 N.M	
Maximum horizontal load	100 KG	
Maximum radial load	50 KG	
Maximum speed ②	600 rpm	
Platform quality	12.5 kg	
Gas supply requirements	80 psi \pm 5 psi, with an air filter less than 0.25 μ m	
Platform material	Aluminium	
mean time between failures	20000 Hours	

NOTES:

(1) Adaptation - AS feedback, configure linear amplifier;

(2) No load, corresponding power amplifiers need to be configured;

(3) The default test point position is 25mm above the tabletop, and the performance indicators of single axis and multi axis systems are related to the actual load and working point position;
 (4) The cylinder gas supply needs to be equipped with a triple air filter, which must be clean, dry, and filtered to particles below 0.25um. It is recommended to use nitrogen gas with a purity of 99.9%. The air pressure can be adjusted according to the actual load weight of the platform.

(5) To prevent insufficient air pressure in the air bearing, it is recommended to install an air pressure switch and input the signal to the emergency stop (E-STOP) port connected to the motion controller.











fixation-girder stage

Parameter Table

PDM - DLXY -	400 - 400	- YT	- SZ
Platform model	Trip:23MM	Platform options	Feedback options
	unit: mm	Original factory standard	T Resolution digital input SZ
	400 600 800	Customer customized loading platform	T analog input MN

Application scenarios

OLED cutting/PCB drilling/CNC machining/biotechnology/IC packaging/wafer inspection

Structural characteristics

Product Introduction



- Adopting ironless linear motor control
 High load, high precision, large stroke, high rigidity
 The precision platform is dust-proof
- · Centralized oil injection, metal grounding function

Customizatio

Larger itinerary can be customized

Fixed beam gantry platform

PDM-DLXY series specifications

Parameter Table

Platform model	PDM-DLXY-400-400-100	PDM-DLXY-600-600-100	PDM-DLXY-800-800-100
Effective stroke	400*400*100	600*600*100	800*800*100
positioning accuracy	±2 μm	±2 μm	±2 μm
Bi directional repetitive positioning acc	uracy ±1 μm	±1 μm	±1 μm
pitch	15 arc sec	20 arc sec	25 arc sec
yaw	15 arc sec	20 arc sec	25 arc sec
roll	15 arc sec	20 arc sec	25 arc sec
Straightness	±3 μm	±5 μm	±8 μm
resolution		100 nm	
Maximum acceleration		1 g	
maximum speed		1 m/s	
Y-axis load		60 KG	
Z-axis load		12 KG	
X-axis		221 N	
Continuous thrust Y-axis		393 N	
X-axis		1248 N	
Peak thrust of P Y-axis		2830 N	
Minimum step quantity		500 nm	
Platform quality	1400 kg	1500 kg	1700 kg
Platform material		Marble	
mean time between failures		20000 Hours	

External dimensions













Platform model	Α	В	С	D
PDM-DLXY-400-400-100	1280 mm	1100 mm	605 mm	16 mm
PDM-DLXY-600-600-100	1280 mm	1360 mm	705 mm	16 mm
PDM-DLXY-800-800-100	1480 mm	1560 mm	905 mm	24 mm



XY cross stage

Model Naming Rules

PDM - DJXY - 500 - 500 SZ YΤ _ **Platform model** Trip:23MM **Platform options** Feedback options Resolution Company: mm Original factory standard installation hole position ΥT SZ digital input 500 800 Customer customized loading platform analog input DT MN

Application scenarios

OLED cutting/PCB drilling/CNC machining/biotechnology/IC packaging/wafer inspection

Product Introduction



Customizatior

It can be evaluated and customized according to customer needs such as configuration, itinerary, load, special structure, etc



XY Cross Platform

PDM-DJXY series specifications

Parameter Table

Platform	model	PDM-DJXY-500-500	PDM-DJXY-800-800
Effective stroke		500 mm*500 mm	800 mm*800 mm
positioning accuracy		±2 μm	±2 μm
Bi directional repetitive	e positioning accuracy	±1 μm	±1 μm
pitch		15 arc sec	20 arc sec
yaw		15 arc sec	20 arc sec
roll		15 arc sec	20 arc sec
Straightness		±3 μm	±5 μm
resolution			100 nm
Maximum acceleration	ו		1.5 g
maximum speed			1.5 m/s
Product load			40 KG
Continuous thrust	X-axis		170 N
	Y-axis		659 N
	X-axis		850 N
Peak thrust of P	Y-axis		3298 N
Minimum step quantity	/		500 nm
Platform quality		450 KG	720 KG
Platform material			marble
mean time between fa	ilures	2	0000 Hours

Note: The above test data was obtained in a laboratory environment, with the test point located 25mm above the center point, using a linear amplifier&Renishaw laser interferometer

Overall dimension



1150mm

200 mm

460 mm

1200 mm

PDM-DJXY-800-800

387 mm



H-type plane air floating stage

Parameter Table



Application scenarios

Suitable for wafer inspection applications of different sizes and processes

Product Introduction



ustomizatio

It can be evaluated and customized according to customer needs such as configuration, itinerary, load, special structure, etc

H-shaped flat air floating platform

PlaneH series specifications

Parameter Table

Platform model	PLM-PlaneH-XY-400	
Effective stroke	400 mm×400 mm	
positioning accuracy	±0.3 µm	
Bi directional repetitive positioning accuracy	±0.2 μm	
pitch	2.5 arc sec	
yaw	2.5 arc sec	
Straightness	±1.5 μm	
Flatness	±1.5 μm	
resolution	1 nm	
Maximum acceleration	0.5 g	
maximum speed	500 mm/s	
Maximum horizontal load	30 KG	
Continuous thrust	Upper axis: 204N Lower axis: 510N	
Peak thrust	Upper axis: 1152N Lower axis: 2880N	

Note: The above test data was obtained from a linear amplifier in a laboratory environment, with the test point located 25mm above the center point

Overall dimension













XYR AOI inspection stage

Parameter Table

Platform model		PDM-X160-Y160-R30-AOIMJ				
axial	X-axial	Y-axial (Dual motor)	R-axial			
Motor model	PU-60A-1	PU-60A-2	PD170			
Continuous thrust	170N	326.8 N	5 N.m			
Peak thrust	850N	1649 N	14 N.m			
persistent current	4.1 Arms	4.0 Arms	1.4 Arms			
peak current	20.7 Arms	20.0 Arms	4.2 Arms			
	mecha	inical parameters				
shafting	X-axial	Y-axial	R-axial			
Effective stroke	160	160	±15°			
load	DD+5kg	X+DD+5kg	5kg			
speed	1 m/s	1 m/s	120 rpm			
acceleration	1G	1G	-			
Pause time	-	-	-			
repeatability	±1 µm	±1 μm	±1.5 arc sec			
positioning accuracy	±2 μm	±2 μm	±3 arc sec			
Straightness	±2 μm	±2 μm	-			
Flatness	±2 μm	±2 μm	-			
End face adjustment	-	-	±2 μm			
Overall plane jumping		10 µm				
Installation method		level				

Application scenarios

Mainly used in various fields such as automotive electronics, display inspection (digital tubes, LCD screens, LED displays), medicine, food, precision parts processing, size measurement, product positioning, etc. The purpose of measuring, counting, testing, and intelligent judgment after the product is run to the corresponding position

Product Introduction

	High precision and high stability direct drive structure design	Str	·Adopting XYR stacking structure, ironless linear motor direct drive control,
Prod	Non contact high-precision grating ruler	uctur	no cogging effect, smooth operation at low speeds (with small speed fluctuations)
uct F	·XY adopts high-precision linear guide rail	al ch	·DD end face runout is less than 2um
eatu	The itinerary, size, and cables can be customized according to customer requirements	aract	\cdot The overall planar runout of the assembled platform is less than 10um
ſes	Equipped with a non-contact high-precision grating ruler, it has excellent performance	eristi	·The repeatability of the entire journey is less than ± 1 um
		ß	·Positioning accuracy less than ± 2um

It can be evaluated and customized according to customer needs such as configuration, itinerary, load, special structure, etc



XYR AOI Testing Platform PDM-X160-Y160-R30-AOIMJ specification





XYZ AOI inspection stage

Parameter Table

Platform model	PDM-X500-Y400-Z10-ZKHY				
axial	X-axial	Y-axial	Z-axial		
Motor model	PU-30B-3	PU-30B-3 (Shuangdong Son)	-		
Continuous thrust	153 N	153 N	23 N		
Peak thrust	884 N	884 N	170 N		
persistent current	2.54 Arms	2.54 Arms	-		
peak current	8.84 Arms	8.84 Arms	-		
	mecl	hanical parameters			
Effective stroke	500 mm	400 mm	10 mm		
load	Z-axial+5.5 kg	Z-axial+X-axial+5.5 kg	5.5 kg		
maximum speed	600 mm/s	600 mm/s	100 mm/s		
Work speed	200 mm/s	100 mm/s	100 mm/s		
Vertical straightness	±2 μm	±2 μm	±2 μm		
acceleration	0.6 g	0.6 g	0.3 g		
Pause time	-	-	-		
repeatability	±1 µm	±1 μm	±1 µm		
positioning accuracy	±2 μm	±2 μm	±2 μm		
Horizontal straightness	±2 μm	±2 μm	±2 μm		
PITCH	±5 arc sec	±5 arc sec	-		
YAW	±5 arc sec	±5 arc sec	-		
orthogonality	±	5 arc sec	-		
Z-axis corresponding frequency		3µm@ 230nm@50Hz			
Overall plane jumping		-			
Installation method		Horizontal installation			

Application scenarios

A high-precision three-axis high-precision motion table with a three-axis stacked structure, suitable for industrial projects requiring high precision and efficiency such as laser processing, optical manufacturing and testing

Product Introduction

	·Design of three-axis direct drive structure		\
ъ	-Z-axis direct drive lift structure	$\cdot Adopting\;XYZ\;stacking\;structure,\;ironless\;linear\;motor\;direct\;drive$	
rodu	-Z-axis with built-in pneumatic balance configuration, maximum load of 10kg	control, no cogging effect, smooth operation at low speeds	
ct Fea	·XY adopts high-precision linear guide rail, and Z-axis adopts anti creep cross	(with small speed fluctuations)	
ature	roller guide rail	-Equipped with a non-contact high-precision grating ruler,	
0)	•XY adopts a marble base, with travel dimensions customized according to	and repeated positioning accuracy. The movement is smooth	
	customer requirements	and the force is stable	
		·XY axis stacked structure, using marble base, high stability,	
Cus		Z-axis direct drive horizontal lifting structure, directly moving load	
stomiz	It can be evaluated and customized according to customer needs such as configuration,	lifting, built-in balance cylinder, stroke 10mm	
ation	········, , , ····· , ······· , ···		/



XYZ AOI Testing Platform PDM-X500-Y400-Z10-ZKHY specification











LED chip inspection stage

Parameter Table

Platform model			PDM-G5		
axial	X0-axial	Y0-axial	Y1-axial	Z0-axial	Z1 轴
load	30 kg	12 Kg	40 kg	30 kg	12 kg
positioning accuracy	+/- (3+L/250) μm	+/- 15 μm	+/- 10 μm	12 mm Minimµm	12 mm Minimµm
trip	2050	Update to1400mm	194mm	-	-
Linear axis length	3140 mm	mm	mm	-	-
Sliding table length	890 mm	230 mm	mm	-	-
resolution	5 nm or better	0.1µm or better	0.1µm or better	0.2 µm	0.2 µm
acceleration	0.5G (Average)@ 66.7% Jerk	0.5G (Average)@ 66.7% Jerk	0.25G (Average)@ 66.7% Jerk	50 mm/sec^2	50 mm/sec^2
speed	1000 mm/s(Max)	1000 mm/s (Max)	500 mm/s (Max)	-	-
Speed fluctuation	0.2% Max @Velocity = 400mm/s	-	-	-	-
repeatability	+/-1 μm	+/-1 μm	+/-1 µm	+/- 1 μm	+/- 0.1 µm
Vertical straightness	+/-15 μm	+/-10 μm	+/- 12 μm over fμll range	-	-
Horizontal straightness	+/- 2 μm over 200mm+/- 15 μm over fμll range	+/-10 µm	+/- 10 µm	-	-
setting time	200 msec @ 0.2µm p-p	200 msec @0.2µm p-p	200 msec @0.2µm p-p	-	-
X0Y0 orthogonal	20	µm p-p	-	-	-

Application scenarios

Suitable for the large panel wick detection industry

Product Introduction

	·Precision linear guide rail			
Pr	·Ironless motor		Struc	·Longmen structure, high stability
oduct	·Ultra high speed stability		tural	·Low Abbe error
Fea	·Balancing large travel, high precision, and heavy load		chare	Compact platform structure with strong driving capability
tures	·Large detection area		acteri	
	·Multiple models can be customized from small to large generations		stics	
)		

Customizatio

It can be evaluated and customized according to customer needs such as configuration, itinerary, load, special structure, etc



LED wick detection platform

PDM-G5 specification



External dimensions









PCB board LDI exposure stage

Parameter Table

Platform model	F	SW-K1195-X900-2Y1350-	Z20	
shafting	x-axis	Y1/Y2-axis	Z1/Z2-axis	K-axis
trip	900 mm	1350 mm	20 mm	1195 mm
load	120 kg	≥ 55KG+Z-axis weight	≥55KG	3(Side Hanging)
Encoder resolution	0.1 µm	0.1 µm	20 µm	0.1 µm
Minimum step	0.5 µm	0.5 µm		0.5 µm
Linear positioning accuracy	/ ±2.5 μm	±2.5 μm	±15 μm	±2.5 μm
Bidirectional repeatability	±1.5 μm	±1.5 μm	±8 μm	±1.5 μm
Horizontal straightness	±8 μm	±5 μm	±5 μm	±10 μm
Vertical straightness	±12 μm	±12 μm	±5 μm	±10 μm
yaw	5 arc sec	5 arc sec	20 arc sec	±15 μm
pitch	10 arc sec	10 arc sec	X. A point 300mm away from the cente the Y direction, during a 20mm mover along the Z axis, Maximum error in Z direction ± 30um	er in lent
roll	10 arc sec	-	-	±10 μm
yaw	±2.5 arc sec/50mm	-	-	-
Pitch	±5 arc sec/50mm	-	-	-
Y1 Y2, X verticality (4.1 arc sec Converted to a jump of 10um in t	he micrometer)	-	-
Y1, Y2 parallelism	-	±3 μm	-	-
maximum speed	500	500 mm/s	15 mm/s	500 mm/s
Maximum acceleration		5000) mm/s 2	
Setting time for ± 0.5um position threshold	<0.1/50mm <0.1/700mm at 500mm/s 0.5G acceleration, 50000 acceleration, under hanging load conditions	<0.1S/1mm <0.1S/500mm	-	<0.1/50mm <0.1/700mm Under the conditions of 500mm/s, 0.5G acceleration, 50000 acceleration, and hanging load
speed stability	-	<1% (50 ~500mm/s)	-	-
Verticality of K-axis and Y-ax	is -	-	-	4.1 arc sec (Converted to a jump of 10um in the mic

Application scenarios

Mainly used in semiconductor production lines, microelectronics production, LCD displays High precision and efficiency are required in industrial projects such as LCD displays, circuit board production, and PCB products



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1850

External dimensions

PCB board LDI exposure platform

PSW-K1195-X900-2Y1350-Z20specifications



Product Introduction

Product Features

Customizatio



It can be evaluated and customized according to customer needs such as configuration, itinerary, load, special structure, etc

Positioning accuracy less than ± 2.5 um



IC carrier board LDI exposure air-floating stage

Parameter Table

Platform model			PDM-2K	600-Z10-X160-Y1	350-LDI		
axial	x-axis	Y-axis	Z -axisXY On the platform	Mounted on the Z-axis crossbeam	Z-axis on the K-axis	K1/K2 axis	Small X-axis
trip	160mm	1350 mm	10 mm	10 mm	20 mm	800 mm	700 mm
form	-	-	-	Dual motor dual gra	ating -	-	-
load	≥ Z-axis+10kg	≥10 Kg	≥10 KG	≥30 KG	≥3KG	3 (Side Hanging) +Small Z-axis	3 (Side Hanging)
Encoder resolution	0.05µm	0.05 µm	-	0.1 µm	20 µm	0.1 µm	0.1 µm
Minimum step	0.5 µm	0.25 µm	20 µm	0.5 µm	20 µm	0.5µm	0.5µm
Linear positioning accura	cy 1μm	1 µm	6 µm	5 µm	6 µm	4 µm	4 µm
Bidirectional repeatability	0.5 µm	0.5 µm	4 µm	3 µm	4 µm	2 µm	2µm
maximum speed	300 mm/s	300 mm/s	15 mm/s	-	-	8 µm	8µm
Maximum acceleration	0.2 mm/s ²	2000 mm/s2	-	-	-	8 µm	8µm
+Setting time for 0.5um	<0.1S/1 mm	<0.1S/1 mm					
position threshold (s)	<0.1S/150 mm	<0.1S/500 mm	-	-	-	-	-
speed stability	-	<0.5% (30~300mm/s)	-	-	-	-	
Controller PSO	-	Resolution of 0.05 µ m	ı –	-	-	-	-
	-	Pulse output frequenc ≥2.4MHz	y _	-	-	-	-
Bidirectional straightne	ess -	-	-	3 µm	-	-	-
Horizontal straightness	s -	-	8 µm	8 µm	8 µm	-	-
Vertical straightness	-	-	8 µm	8 µm	8 µm	-	-
yaw	-	-	8 arc sec	2.5 arc sec	10 arc sec	6 arc sec	6 arc sec
pitch	-	-	8 arc sec	8 arc sec	10 arc sec	8 arc sec	8 arc sec
roll	-	-	-	-	-	8 arc sec	8 arc sec
maximum speed	-	-	15 mm/s	15 mm/s	15 mm/s	500 mm/s	500 mm/s
Maximum acceleration	n -	-	-	-	-	4000 mm/s 2	4000 mm/s 2
Verticality (orthogona K2 axes and Y-axis	lity) of K1,	-	-	-	-	3 arc sec	-
Setting time for ± 0.5um position threshold	-	-	-	-	-	<0.1/50 <0.1/700mm at 500r 50000+acceleration,	0mm nm/s, 0.5G acceleration, under hanging load conditic
Verticality of small X-axis an	d Y-axis -	-	-	-	-	-	3 arcsec
Orthogonality with the K	-axis -	-	-	-	20 arc sec	-	-

Application scenarios

Mainly used in semiconductor production lines, microelectronics production, LCD displays LCD displays, circuit board production, PCB products, and other industrial projects require high precision and efficiency.



IC carrier board LDI exposure air flotation platform PDM-2K600-Z10-X160-Y1350-LDIspecifications











Product Introduction

Product Features	 High dynamic performance XY adopts a fully enclosed air floating guide rail with good stability High precision zero expansion grating feedback is selected, with a low expansion coefficient and minimal influence from temperature drift Z-axis uses magnetic springs to balance the load, customizable The itinerary, size, and cables can be customized according to customer requirements 		•Multi axis air floating platform, using air floating XY stacking structure •Hanging K-axis and Z-axis on the side of the crossbeam (mechanical guide rail) •Direct drive control of ironless linear motor without cogging effect •Smooth operation at low speeds (with minimal speed fluctuations) Equipped with a non-contact high-precision grating ruler, it has excellent dynamic performance, positioning accuracy, and repeatability accuracy
Customization	It can be evaluated and customized according to customer needs such as configuration, itinerary, load, special structure, etc	1	Selection of high-precision grating position feedback for multi axis air flotation platform The repeatability of the entire journey is less than 0.5um, The positioning accuracy is less than 1um.



Wafer cutting stage

Platform model	PDM-X40	00-Y600		
axial	x-axis	Y-axis		
Effective stroke	400 mm	600 mm		
repeatability	≤±1	μm		
Compensation based positioning accuracy	≤±1µm			
Horizontal straightness	≤± 1 μ m (1.5 μ m/within 200 strokes in the middle) ≤±1 μ m			
Vertical straightness	≤±1.5µm	≤±1.5µm		
Verticality between XY	≤5µ	Im		
maximum speed	1000mm/s	300mm/s		
Maximum acceleration	2 G	0.5 G		
load	25kg			
Line length	Outside the	e drag chain3m		
	Motor parameters			
Cooling method	Self cooling	water-cooling		
Continuous thrust	722.6 N	1159.3 N		
Peak thrust	1610	.5 N		
Force constant ± 10%	153.0 N/	Arms		
Reverse electromotive force constant+10%	124.9 Vpeal	k/(m/s)		
Motor constant @ 25	58.2 N/Sqrt	: (W)		
Interphase resistance @ 25	4.6	Ω		
Interphase inductance ± 30%	116.0 mH			
persistent current	4.8 Arms	8.2 Arms		
peak current	14.4 A	Arms		
Continuous thermal power	204.9 W	597.9 W		
Thermal dissipation constant	2.8 W/ C	8.0 W/ C		

Application scenarios

Suitable for various semiconductor industries such as wafer slicing and wafer inspection

Product Introduction



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It can be evaluated and customized according to customer needs such as configuration, itinerary, load, special structure, etc



Wafer cutting platform

PDM-X400-Y600specifications



External dimensions









Laser film removal stage

Parameter Table

Platform model	PDM-X2830-	TY3104
axial	x-axis	Y-axis
trip	2830 mm	3104 mm
load	Y load+Y self weight+100kg	80Kg
maximum speed	1m/s	1m/s
Maximum acceleration	0.5g	0.5g
repeatability	±5µm	±5µm
Compensation based positioning accuracy	±12µm	±12µm
Sports mode	Move 300mm in 0.5 seconds, stay for 1.5 seconds, cycle motion	Move 300mm in 0.5 seconds, stay for 1.5 seconds, cycle motion
Notor model	P8-H150-6	P3-H75-2
Winding code	Т	S
maximum thrust	7605 N	1044 N
continuous thrust	3582 N	374 N
aximum power	22815 W	1566 W
Continuous Power	10746 W	566 W
ositive suction force	11700 N	1746 N
aximum current	43.56 Arms	10.3 Arms
ontinuing current	14.52 Arms	3.28 Arms
rce constant	246.69 N/Arms	113.68 N/Arms
ine back electromotive force coefficient	101.57 Vpeak/m·s^-1	100.36 Vpeak/m·s^-1
ine resistance	2.22 Ohms	8.58 Ohms
ine inductance	66 mH	47.2 mH
ime constant	29.73 ms	5.5 ms
notor constant	135.19 N/√W	32.12 N/√W
Maximum coil temperature	130 °C	130 °C
Aaximum terminal voltage	600 VDC	310 VDC
Coll length	532 mm	193 mm
Coil quality	30.3 kg	2.8 kg
Magnetic track quality	15.1 kg/m	6.6 kg/m
pole pitch	42 mm	25 mm

Application scenarios

Suitable for ultra large format laser film removal platform



Laser film removal platform

PDM-X2830-TY3104specifications









It can be evaluated and customized according to customer needs such as configuration, itinerary, load, special structure, etc

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Air-floating gantry marble stage

Parameter Table

Platform model	PDM-2Y800-SQ
axial	Y-axis (lower axis)
Travel	810 mm (effective travel 770 mm)
load	110Kg
maximum speed	0.5m/s
Maximum acceleration	0.5g
Horizontal straightness	±2.5 µm
Vertical straightness	±2.5 µm
repeatability	±2 μm
Compensation based positioning accuracy	±5µm
Deviation (aw)	±3 arc sec
Pitch	±3arc sec
Sports mode	Move 300mm in 0.5 seconds, stay for 1.5 seconds, cycle motion
Motor model	PU-30B-4
Winding code	S
maximum thrust	1152 N
continuous thrust	204 N
maximum power	1728 W
Continuous Power	306 W
Positive suction force	0 N
Maximum current	14.3 Arms
continuing current	2.54 Arms
force constant	80.6 N/Arms
Line back electromotive force coefficient	6 Vpeak/m·s^-1
Line resistance	13.2 Ohms
Line inductance	4.28 mH
time constant	0.33 ms
motor constant	15.69 N/√W
Maximum coil temperature	130 °C
Maximum terminal voltage	310 VDC
Coil length	241 mm
Coil quality	0.8 kg
Magnetic track quality	17.5 kg/m
pole pitch	30 mm

Application scenarios

Suitable for the photovoltaic coating industry



Air floating gantry marble platform

PDM-2Y800-SQspecifications



External dimensions









Product Introduction



Oual drive layout can be paired with bilateral Z-axis for use
 Ompact platform structure with strong driving capability

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It can be evaluated and customized according to customer needs such as configuration, itinerary, load, special structure, etc



Hollow precision bonding positioning stage

Parameter Table

Platform model	PM-X340-Y420-RB0.5		
	mechanical parameters		
load	kg	30	
trip	mm	X.340 Y.420	
resolution	μm	0.5	
positioning accuracy	μm	10	
repeatability	μm	±3	
Horizontal straightness	μm	10	
Vertical straightness	μm	10	
Installation method		level	
	Motion Parameters		
speed	m/s	1	
acceleration	mm/s²	20	
stop time	s	0.09	
	ŀ	Accessory	
encoder	PCS	2	
Photoelectric switch	PCS	2	
rail	PCS	7	
drag chain	PCS	2	
	Мо	tor parameters	
Motor model	P3-H55-3		
Continuous thrust	Ν	413	
Peak thrust	Ν	1113	
persistent current	Arms	3.23	
peak current	Arms	8.68	
Base material	aluminium		
Matrix flatness	20 μm		

Application scenarios

This platform is a precision motion table with a hollow structure, featuring large-sized through holes and high dynamic performance to meet wafer mounting and inspection applications. It is also suitable for other high-end manufacturing industries such as CCD imaging and LED packaging inspection



Hollow precision solidification positioning platform

PM-X340-Y420-RB0.5specifications

Specifications



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Product Introduction

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 Stacked 	layout
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- · Compact hollow structure
- Adopting high-precision linear guide rail
- High dynamic performance, high precision
- The Y-axis is driven by a dual drive linear motor
- · The itinerary, size, and cables can be customized

Structural characteristics

Adopting a compact hollow outer structure with stacked layers
The working point position is lowered, and the grating feedback position is close to the working surface, which is crucial in wafer inspection. The Y-axis is driven by a dual drive linear motor
Can provide high thrust, speed of 1m/s, and accurate positioning

Product Features

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It can be evaluated and customized according to customer needs such as configuration, itinerary, load, special structure, etc

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Gantry dual-drive precision dispensing stage

Parameter Table

Platform model	PDM-X2	00-TY400-DN
	Motor parameters	
axial	x-axis	Y1Y2-axis
Motor model	PU-30A-4-S-5M-HALL	PU-30A-4-S-5M-HALL
Continuous thrust	104 N	104 N
Peak thrust	576 N	576 N
persistent current	2.54 Arms	2.54 Arms
peak current	14.3 Arms	14.3 Arms
	Mechanical paramete	rs
axial	X-axis	Y1Y2-axis
Effective stroke	200 mm	400 mm
load	35 kg	35 kg+X-axis
speed	200mm/s	200 mm/s
repeatability	±0.5 μm	±0.5 μm
positioning accuracy	±1 μm	±1μm

Application scenarios

The gantry dual drive platform is a high-precision Cardil dual drive gantry system, with superior performance used in high-precision and high-efficiency industrial projects such as surface mount machines, scanning processing, automated assembly, and visual observation

Product Introduction

Product Features	 Communication brushless dual drive gantry structure High repeatability positioning accuracy Maximum speed exceeding 2m/s, acceleration exceeding 2G High dynamic performance, high precision Z-axis/rotation axis can be configured according to customer requirements The itinerary, size, and cables can be customized according to customer requirements 		Structural observatoristics	 Adopting ironless linear motor and equipped with non-contact grating ruler The repeatability of the entire journey is less than ± 0.5um Positioning accuracy less than ± 1um Has excellent dynamic performance and positioning accuracy. The gantry shaft adopts a dual direct drive structure, which has strong driving capability The crossbeam shaft adopts a single linear motor structure to achieve high-speed scanning
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It can be evaluated and customized according to customer needs such as configuration, itinerary, load, special structure, etc



Longmen dual drive precision dispensing platform

PDM-X200-TY400-DN specifications

External dimensions









Lithium battery welding stage

Parameter Table

Platform model	PM-X860-Y700-RB0.1		
	mechanical parameters		
load	kg	X=Z+15 Y=35	
trip	mm	X=860 Y=700	
resolution	μm	0.1	
positioning accuracy	μm	±2	
repeatability	μm	±1	
parallelism	μm	±4	
Vertical straightness	μm	±4	
Motion Parameters			
speed	m/s	0.8	
acceleration	mm/s²	10	
stop time	S	0.5	
	a	ccessory	
Driver	PCS	3	
encoder	PCS	3	
Photoelectric switch	PCS	9	
rail	PCS	6	
	Motor parameters		
Motor model	P3-H55-2		
Continuous thrust	Ν	276	
Peak thrust	Ν	742	
persistent current	Arms	3.23	
peak current	Arms	8.68	
Base material	marble		

Application scenarios

This platform is mainly used for lithium battery welding and laser cutting platforms


Lithium ion welding platform

PM-X860-Y700-RB0.1 specifications

External dimensions









Product Introduction



- · The X double Y fixed gantry platform is a linear motor platform
- ·Marble gantry structure design, with good rigidity and high stability
- · Multiple X axes can be added to the marble base
- The Y-axis stroke of the gantry frame can be customized to
- improve work efficiency

Structural characteristics

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It can be evaluated and customized according to customer needs such as configuration, itinerary, load, special structure, etc

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